

## GlobalWafers Japan Co., Ltd. News Release

March 4, 2016

Subject: Final report for exhaust scrubber system damage issue at Tokuyama plant

Exhaust scrubber system damage was occurred on Tokuyama plant at January 20<sup>th</sup>. Fortunately no human suffering was reported however, we apologize for the worries and inconvenience to the neighborhood. On March 3, damaged exhaust scrubber system was fully recovered and resumed production. We continue to make a lot of effort for prevent recurrence and safety operation..

### Outline of the issue

#### 1. Location of the issue

GlobalWafers Tokuyama plant building 2

Address: 2-1-32 Eguchi, Shunai city, Yamaguchi pref. Japan

#### 2. Date & time of occurrence

6:15pm Wednesday January 20<sup>th</sup> 2016

#### 3. What happened?

There was a small fire on duct of exhaust scrubber systems. The fire was put out by two CO2 fire extinguishers at 6:50pm. On-site investigation was made by police and fire department and completed on January 21<sup>th</sup>..

#### 4. Loss & damage

Human suffering: No human suffering was verified. No damage and evacuation was verified for neighborhood.

Property damage: Part of exhaust scrubber system was damaged.

#### 5. Root cause

Due to malfunction of the valve, air was flow in exhaust duct where hydrogen gas was contained in exhaust gas flow. Small fire was occurred in scrubbers.

#### 6. Status of recovery

Production tools connecting with damaged exhaust scrubber system has resumed operation by adding safety measure which came from root cause analysis since evening of March 3. Our production line was fully recovered.

If you have any question, please contact following.

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